

Specification Amendments

Please amend the text at page 3, line 16 through page 4, line 22:

The present invention meets the need in the art by providing an apparatus and method that identifies, monitors, and tracks facilities maintenance. The apparatus comprises an interactive information storage device configured for receiving and retaining at least one facility profile. The facility profile includes a facility identification, at least one process area descriptor identifying a functional subdivision of a facility and at least one substrate comprising a maintainable item associated with each process area [descriptor]. Associated with each substrate is a substrate condition having a quantitative value representative of a subjective qualitative assessment of the condition of the substrate, a substrate environment having a quantitative value representative of a subjective qualitative assessment of the environment of the substrate, a substrate process priority having a quantitative value representative of a subjective assessment of the criticality of the substrate to the process area, and a substrate area. An analyzer evaluates the substrate condition, substrate environment, and substrate process priority to determine a quantitative substrate ranking. An estimator applies standard work information to the substrate condition, substrate environment, substrate process priority, and substrate area, to determine substrate maintenance estimates. A reporter generates maintenance specifications of the substrate maintenance estimates and substrate ranking for a selected one of the facility profiles.

In another aspect, the present invention provides a method for identifying, monitoring, and tracking of facilities maintenance, comprising the steps of:

(a) subdividing a facility into separate process areas representative of functional subdivisional areas of the facility;

(b) identifying within each process area at least one substrate comprising a maintainable item associated with the process area together with a substrate condition having a quantitative value representative of a subjective qualitative assessment of the condition of the substrate, a substrate environment having a quantitative value representative of a subjective qualitative assessment of the environment of the substrate, and a substrate process priority having a quantitative value representative of a subjective assessment of the criticality of the substrate to the process area;

(c) analyzing the substrate condition, substrate environment, and substrate process priority to determine a quantitative substrate ranking; and

(d) generating maintenance specifications using a substrate maintenance estimates and substrate ranking for a selected one of the facilities.